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FLAT PANEL X-RAY DETECTOR

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Part 1

Flat Panel X-Ray Detector

State of the art and limitations



- The replacement of the medical radiographic film has been the main driver, during the last decade for large area X-ray detectors development
- Several Flat Panel X-Ray detectors (FXD) are now available, all of them using Amorphous Silicon Technology, for digital radiography system
- FXD for dynamic imaging (30 fps) of the heart have been recently introduced



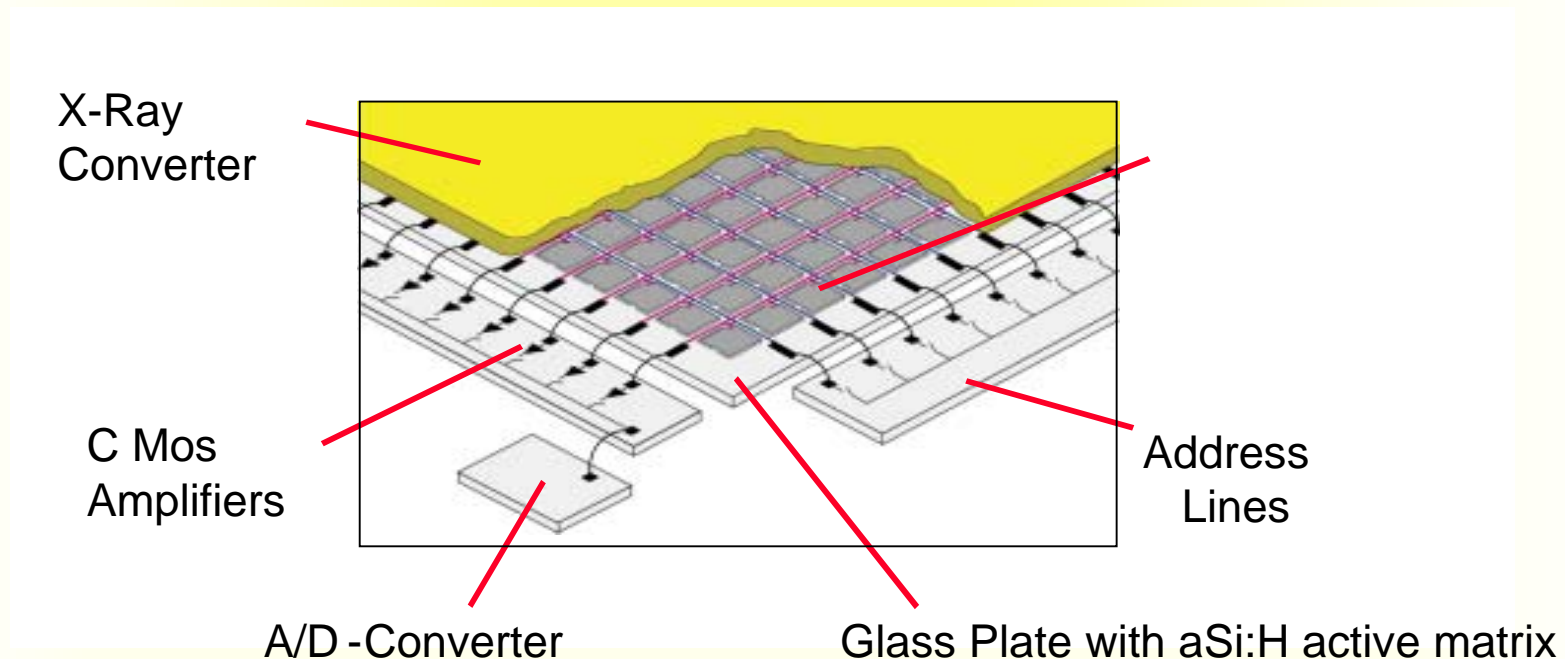
Requirements for film replacement

	General radiography	Mammography
Size	> 40 x 40 cm	>18 x 24 cm
Pixel size	~ 150 μm	60-100 μm
Typical nb of incid.X/pel	~1000	~5000
Corresponding dose	2.5 μGy	100μGy
Energy range	30-120 keV	~20 keV
Input equiv. noise	< 5 X quanta	< 5 X quanta
Dynamic range	12 bit	12 bit
Exposure / Readout time	.5 s / 1 s	1s / 5 s



FXD general architecture

- X-Ray converter : scintillator or photoconductor
- Active aSi:H readout matix
- External readout Amplifiers/multiplexers and lines drivers



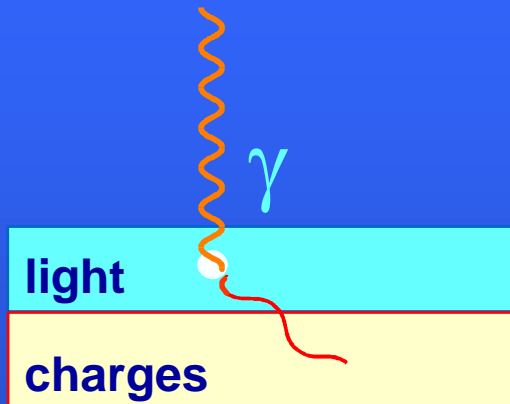


X-Ray Conversion Direct / Indirect

Two designs are currently used

Indirect Conversion

(scintillator - photodetector)

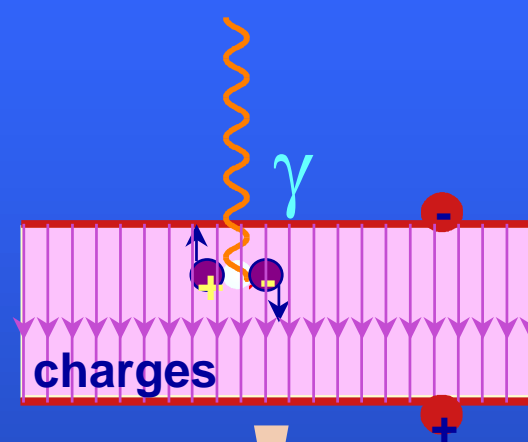


1000 charges
at 60 keV

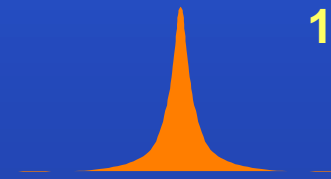


Direct Conversion

(semi-conductor)



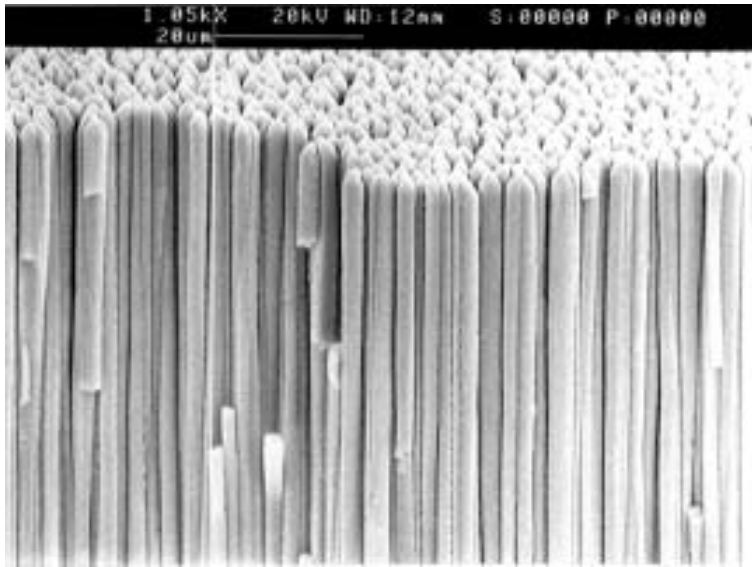
10 000 charges
at 60 keV





Indirect Conversion

State of the art : Thallium doped Cesium Iodine (CsI) screen



- Vapour grown
- Tl doped for green emission
- Columnar structure
- Large area 43cm x 43 cm
- Thickness ~ 500 - 600 μ m
- X-ray Absorption : 80 % at 60keV



Advantages :

- High absorption of X-ray :
80% at 60keV (500 μ m)
- Resolution due to CsI needle like structure :
MTF~ 40% at 2lp/mm (pixel 200 μ m)

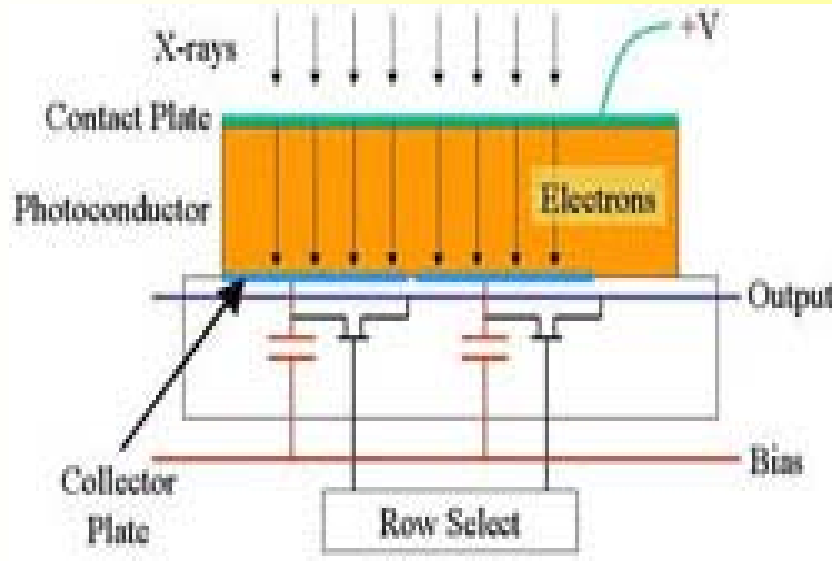
Limitations :

- light scattering effect
- Fill factor limiting the minimum pixel size
64% for 150 μ m pixel size
50% for 100 μ m pixel size
- Sensitivity :
1100 electrons per X-Ray (DN 5)
- Memory effect following stronger exposure :
.1 % after few seconds



Direct Conversion

State of the art : amorphous Selenium photoconductor



- Large area 43cm x 43 cm
- Thickness ~ 500 - 1000 μ m
- Electric field ~10 V/ μ m
- X-ray Absorption : 52 % at 60keV

Direct Conversion : Amorphous Sélénium

Advantages :

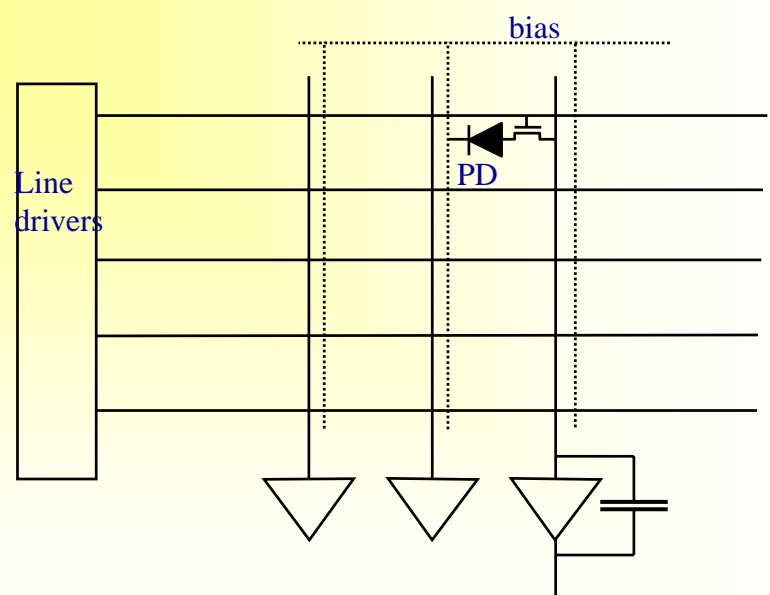
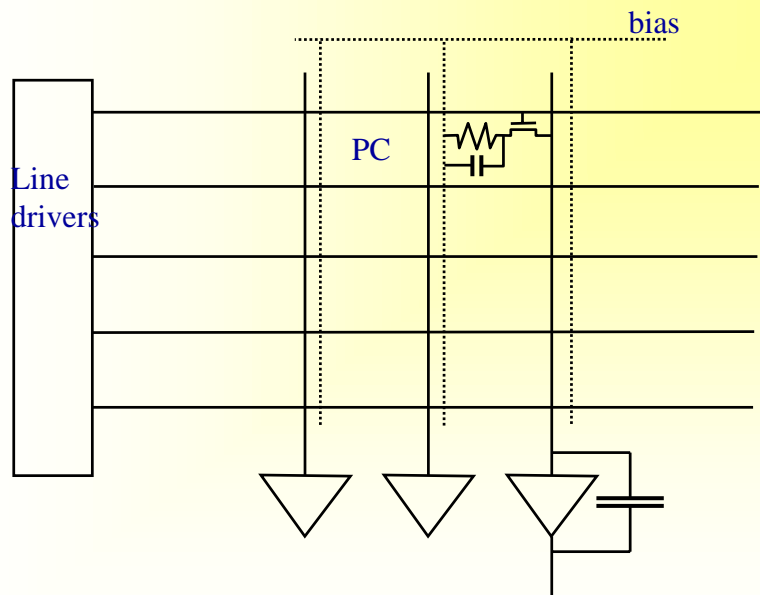
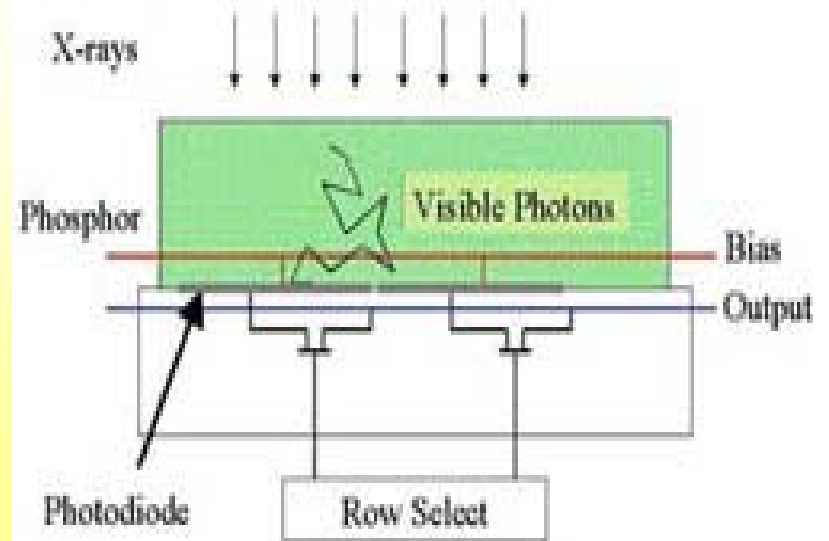
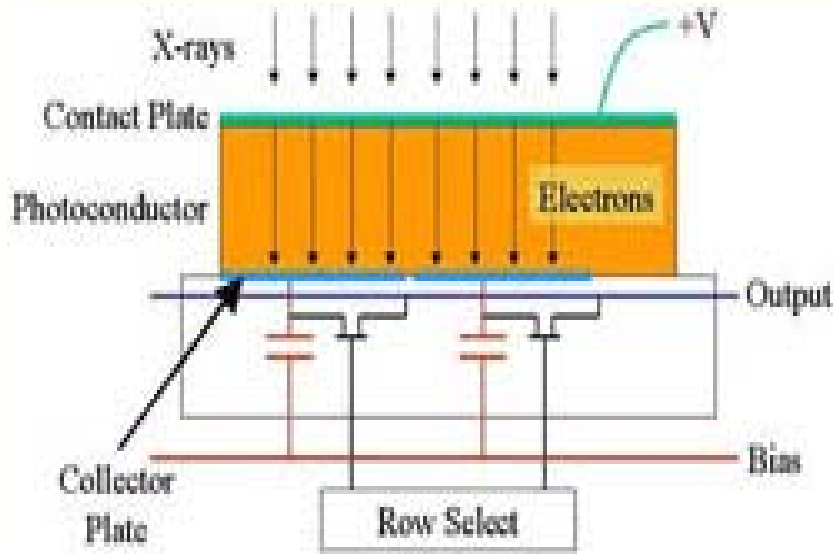
- High resolution :
MTF~ 75 % at 2lp/mm (pixel 150 μm)
- Fill factor :
Almost 100% for 150 μm pixel
- Simpler readout matrix
No photodiode

Limitations :

- absorption of X-ray :
52% at 60keV (500 μm)
- Sensitivity :
1000 charges per X-Ray (DN 5)
- Lag effect :
2% after 33 ms



FXD READOUT ARCHITECTURES



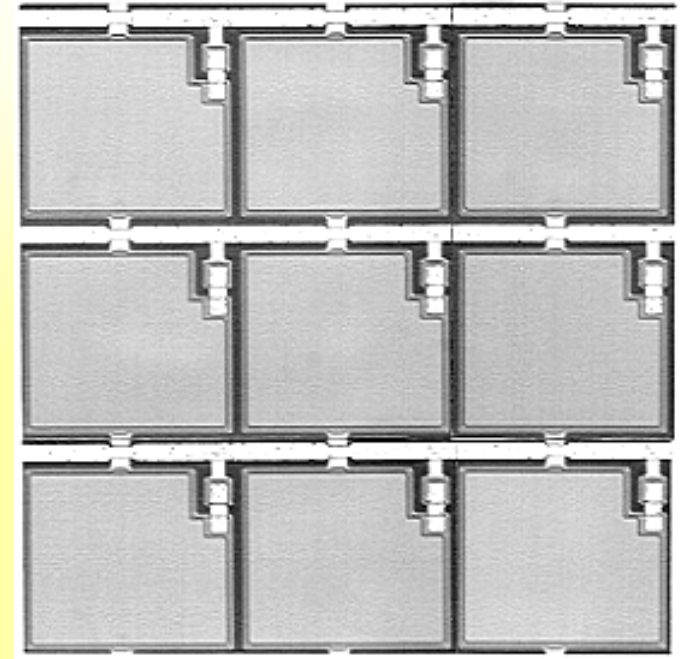


FXD READOUT ARCHITECTURES

- 2D array of aSi-TFT switches addressed by line pulse
- Signal readout by column data bus and by external amplifier

LIMITATIONS :

- No pixel amplification
- Readout noise (~ 1000 electrons) equivalent to signal at Fluoroscopic dose
- Scintillator detectors require specific process for photodiode



150 μm



- The characteristics of commercial XFD are now approaching the maximum values provided by the present concept :
 - Performances for General Radiography are better than film
 - At very low dose used in fluoroscopy and interventional techniques the signal to noise ratio is still the limiting factor for both direct (Se) and indirect design (CsI:Tl)
 - Cost of these detectors remains high

New architectures and new photoconductors materials are required to overcome the present limitations.



Part 2

Flat Panel X-Ray Detector

Future Developments



- To get a larger number of electrons per quantum X-Ray X-ray photoconduction is an attractive way :
 - Larger number of created charges
 - Spatial resolution is almost independent of thickness and MTF is very close to the theoretical pixel response
- What we need :
 - High absorption (Heavy materials)
 - Low charge pair energy
 - Good transport properties
 - Low dark current (blocking contacts ; high resistivity)
 - Good lag characteristics
 - Large area manufacturing process (40cm x 40 cm)
 - Low manufacturing cost : ~ 1000 €for a 40 cm x 40 cm layer



DIRECT CONVERSION MATERIALS

	Poly CdTe	Poly HgI ₂	Poly PbI ₂	Amorphous Selenium	Poly PbO
Atomic Number	48-52	80-53	82-53	34	82-8
Density	5.9	6.4	5.5	4.3	?
Energy band gap eV	1.5	2.1	2.3	2.2	
Charge Pair Energy eV	4.5	5.5	6.6	50 (effective)	15
Processing temperature °C	500	100	200	80 (Substrate)	



DIRECT CONVERSION MATERIALS

- Cadmium Telluride, Mercuric Iodide and lead Iodine are considered as the best candidates for large area X-rays detectors for Medical applications

CdTe & CdZnTe	HgI ₂	PbI ₂
<ul style="list-style-type: none">• CEA LETI• SHIMADZU	<ul style="list-style-type: none">• VARIAN/ RTRR• XEROX/ RMD	<ul style="list-style-type: none">• XEROX/ RTRR

- Further investigations and improvements are required to obtain materials with the required characteristics in **very large area.**



Matrix size : 512 * 512

Pixel pitch : 150 μm

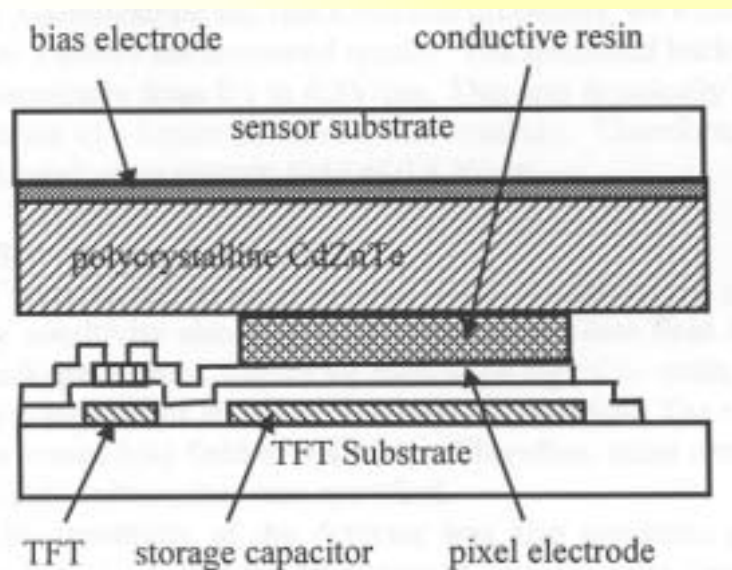
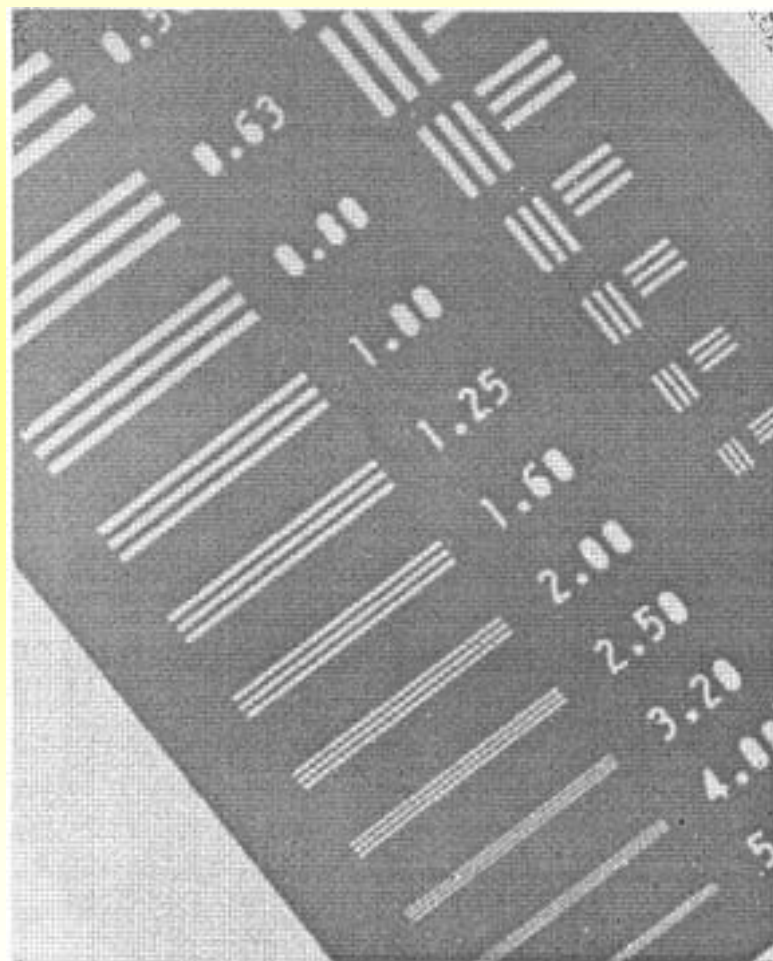


Figure 1 Schematic cross-section of the flat-panel detector with CdZnTe film





SIGNAL INCREASE : PIXEL DESIGN

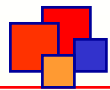
- In present aSi:H Matrix design a single TFT is used as a switch to read out the pixel signal resulting in a signal equivalent to the noise generated by the matrix readout process.
- The incorporation of an amplification at pixel level will overcome this limitation.
- The low charge mobility of aSi:H materials is not suitable for such a design :

a new technology is required



Technologies for future readout matrix

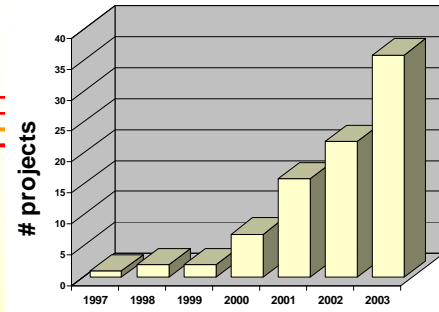
Poly SI	C MOS
<ul style="list-style-type: none">• Relatively high mobility• Low integration<ul style="list-style-type: none">– single pixel amplification• Very large area	<ul style="list-style-type: none">• High mobility (crystal silicon)• High integration<ul style="list-style-type: none">– Pixel functionalities– Matrix drivers– Pixel counting• Relatively large area



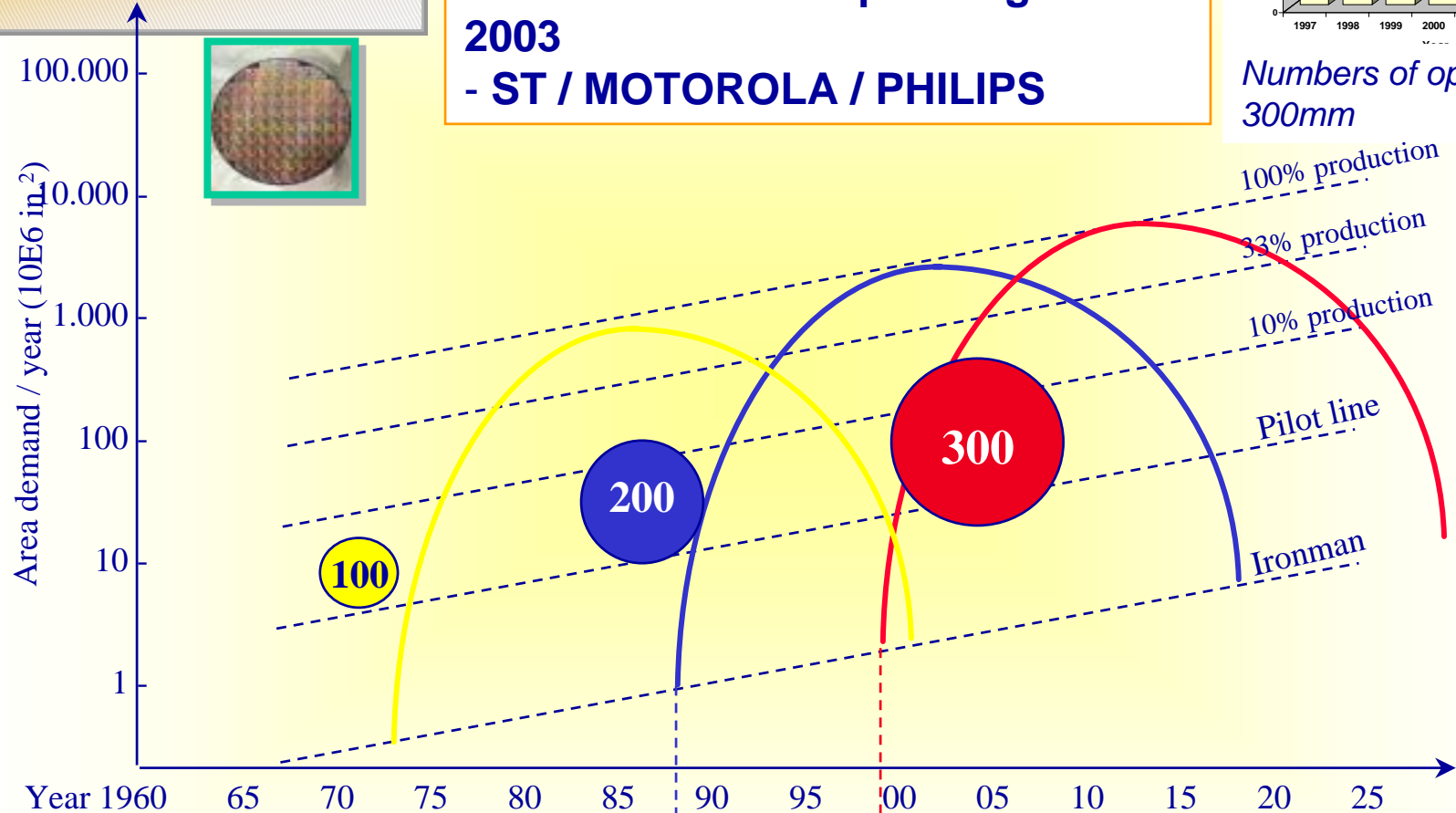
CMOS 12 inches wafer : the future

300 mm

- CCMC Crolles 2 opérating en 2003
- ST / MOTOROLA / PHILIPS



Numbers of operations 300mm



Source : VLSI research,

100 mm

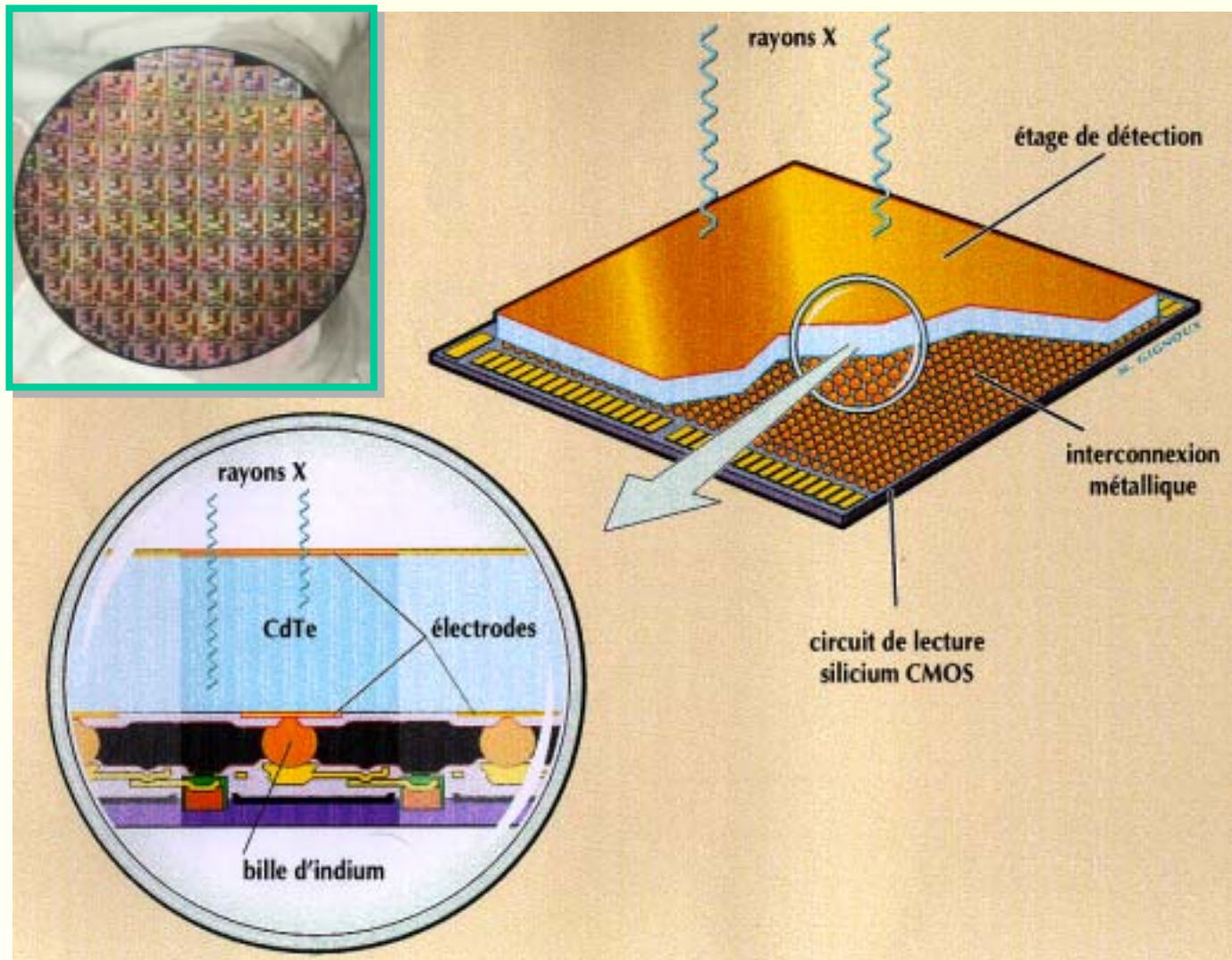
200 mm

300 mm





FXD Direct conversion and CMOS readout





- CMOS allows the design of Digital Counters in individual pixel
- The counting mode will provide :
 - Better **stability** : *temperature, gain*
 - Digital information at pixel level : *insensitive to matrix readout noise*
 - Elimination of **memory effect and lag effect**
 - Spectral information : *multi-energy radiography*
- The two main limitations are :
 - Limitation of the **counting rate** at high dose exposure
 - **power consumption**



CONCLUSION : THE FOUR KEYS FOR FUTURE FXD

**Direct Conversion
Materials**

**CMOS Integrated
readout Matrix**

Coupling Technology

- Hybrid
- Direct deposit ?

Digital counting ?